

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 247866US2S		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Akira HOKAZONO, et al.			
				FILING DATE Herewith		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
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	AL						
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	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES                  NO		
	AO						
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
<i>omv</i>	AW	A.S.W. WONG, et al., "Enhanced Thermal Stability of NiSi Films on 20KEV BF <sub>2</sub> + Implanted (100) Si", SYMPOSIUM B SILICON MATERIAL-PROCESSING, CHARACTERIZATION AND RELIABILITY, MRS 2002 Spring Meeting, April 1-5, 2002, 1 Page					
<i>am</i>	AX	T. OHGURO, et al., "Analysis of Anomalously Large Junction Leakage Current of Nickel Silicided N-Type Diffused Layer and Its Improvement", EXTENDED ABSTRACTS OF THE 1993 INTERNATIONAL CONFERENCE ON SOLID STATE DEVICES AND MATERIALS, 1993 Pages 192-194					
	AY						
	AZ						
Examiner <i>Sharon Magee</i>					<input type="checkbox"/> Additional References sheet(s) attached Date Considered <i>06/21/05</i>		
<small>*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>							